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Docket No.: SUG-187-PCT

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Serial No.: 10/556,063

Confirmation No.: 4291

Applicant: Masatoshi TAKAHASHI, et al.

Art Unit: TO BE ASSIGNED

Filed: November 8, 2005

Examiner: TO BE ASSIGNED

Docket No: SUG-187-PCT

Customer No: 28892

For: Solar Cell and Method of Fabricating the Same

INFORMATION DISCLOSURE STATEMENT - PTO FORM 1449

U.S. PATENT DOCUMENTS			
Examiner Initials*	U.S. Patent Document Number	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
/A.B./	2002/0086557	Matsumura et al.	July 4, 2002
/A.B./	6,349,669 (JP 10-83988)	Matsumura et al.	Feb. 26, 2002
/A.B./	6,291,366	Sano et al.	Sept. 18, 2001
/A.B./	6,225,241 (JP 10-209151)	Miyoshi	May 1, 2001
/A.B./	6,069,094	Matsumura et al.	May 30, 2000

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INFORMATION DISCLOSURE STATEMENT - PTO FORM 1449 - PAGE 2 OF 3

FOREIGN PATENT DOCUMENTS				
Examiner Initials*	Foreign Patent Document Number	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T**
/A.B./	JP 2002-75877 (w/ Eng. Abstract)	Manabu et al.	March 15, 2002	
/A.B./	JP 2000-216163 (w/ Eng. Abstract)	Fujitsu Ltd.	August 4, 2000	
/A.B./	JP 10-209151 (US 6,225,241)	NEC Corp.	August 7, 1998	
/A.B./	JP 10-83988 (US 6,349,669)	Hideki Matsumura	March 31, 1998	
/A.B./	JP 9-205209 (w/ Eng. Abstract)	Yoda Masato	August 5, 1997	
/A.B./	JP 9-97916 (w/ Eng. Abstract)	Sharp Corp.	April 8, 1997	
/A.B./	JP 8-250438 (w/ Eng. Abstract)	Hideki et al.	Sept. 27, 1996	
/A.B./	JP 8-55858 (US 6,291,366)		Feb. 27, 1996	
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/A.B./	EP 325606	Mobil Solar Energy Corp.	Sept. 7, 1994	
/A.B./	JP 2-500397 (WO 89/00341)	Mobil Solar Energy Corp.	Feb. 8, 1990	
/A.B./	WO 89/00341 (JP 2-500397)	Chaudhuri et al.	January 12, 1989	

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INFORMATION DISCLOSURE STATEMENT - PRO FORM 1449 - PAGE 3 OF 3

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS		
Examiners Initials *	Include Author (CAPITAL LETTERS), title of article, book, magazine, etc. date, page(s), volume-issue number(s), publisher, city and/or country where published	T **
/A.B./	HOLT, J.K. et al., "Hot-Wire Chemical Vapor Deposition of High Hydrogen Content Silicon Nitride for Solar Cell Passivation and Anti-Reflection Coating Applications", <u>Elsevier Science B.V.</u> , April 2003, pp. 37-40, Vol. 430, No. 1-2.	
/A.B./	MOSCHNER, JENS D. et al., "Thermo-Catalytic Deposition of Silicon Nitride - A New Method for Excellent Silicon Surface Passivation," 29th IEEE Photovoltaic Specialists Conference, New Orleans, May 20-24, 2002, pp.174-177.	
/A.B./	MATSUMURA, H. et al., "CAT-CVD Process and Its Application to Preparation of Si-Based Thinfilms", Materials Research Society Symposium Proceedings, San Francisco, April 5-9, 1999, pp. 67-78, Vol., 557.	
/A.B./	KUDO, A. et al., "Study on Improvement on Uniformity of Cat-CVD SiNx Thin Films", <u>Technical Report of IEICE</u> , April 1999, pp. 59-66, ED99-10.	
/A.B./	OKADA, SHINYA et al., "Improved Properties of Silicon Nitride Films Prepared by the Catalytic Chemical Vapor Deposition Method," <u>Japan Journal Applied Physics</u> , Nov. 1997, pp. 7035-7040, Vol. 36, No. 11.	

Examiner Signature	/Allison Bourke/	Date Considered	05/04/2009
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***Examiner:** Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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